Connecting via Winsock to STN

Welcome to STN International! Enter x:x

LOGINID:ssptasmb1637

PASSWORD:
TERMINAL (ENTER 1, 2, 3, OR ?):2

* * * * * * * * * * Welcome to STN International * * * * * * * * * *

NEWS 1		Web Page for STN Seminar Schedule - N. America
NEWS 2	JAN 02	STN pricing information for 2008 now available
NEWS 3	JAN 16	CAS patent coverage enhanced to include exemplified prophetic substances
NEWS 4	JAN 28	USPATFULL, USPAT2, and USPATOLD enhanced with new custom IPC display formats
NEWS 5	JAN 28	MARPAT searching enhanced
NEWS 6	JAN 28	USGENE now provides USPTO sequence data within 3 days of publication
NEWS 7	JAN 28	TOXCENTER enhanced with reloaded MEDLINE segment
NEWS 8	JAN 28	MEDLINE and LMEDLINE reloaded with enhancements
NEWS 9	FEB 08	STN Express, Version 8.3, now available
NEWS 10	FEB 20	PCI now available as a replacement to DPCI
NEWS 11	FEB 25	IFIREF reloaded with enhancements
NEWS 12	FEB 25	IMSPRODUCT reloaded with enhancements
NEWS 13	FEB 29	WPINDEX/WPIDS/WPIX enhanced with ECLA and current U.S. National Patent Classification
NEWS 14	MAR 31	IFICDB, IFIPAT, and IFIUDB enhanced with new custom IPC display formats
NEWS 15	MAR 31	CAS REGISTRY enhanced with additional experimental spectra
NEWS 16	MAR 31	CA/CAplus and CASREACT patent number format for U.S. applications updated
NEWS 17	MAR 31	LPCI now available as a replacement to LDPCI
NEWS 18	MAR 31	EMBASE, EMBAL, and LEMBASE reloaded with enhancements
NEWS 19	APR 04	STN AnaVist, Version 1, to be discontinued
NEWS 20	APR 15	WPIDS, WPINDEX, and WPIX enhanced with new predefined hit display formats
NEWS 21	APR 28	EMBASE Controlled Term thesaurus enhanced
NEWS 22	APR 28	IMSRESEARCH reloaded with enhancements
NEWS 23	MAY 30	INPAFAMDB now available on STN for patent family searching
NEWS 24	MAY 30	DGENE, PCTGEN, and USGENE enhanced with new homology sequence search option
NEWS 25	JUN 06	EPFULL enhanced with 260,000 English abstracts
NEWS 26	JUN 06	KOREAPAT updated with 41,000 documents

NEWS EXPRESS FEBRUARY 08 CURRENT WINDOWS VERSION IS V8.3,
AND CURRENT DISCOVER FILE IS DATED 20 FEBRUARY 2008

NEWS HOURS	STN Operating Hours Plus Help Desk Availability
NEWS LOGIN	Welcome Banner and News Items
NEWS IPC8	For general information regarding STN implementation of IPC 8

Enter NEWS followed by the item number or name to see news on that specific topic.

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* * * * * * * * * * * * * * * * STN Columbus * * * * * * * * * * * * * * * *

FILE 'HOME' ENTERED AT 15:58:27 ON 11 JUN 2008

=> file registry

COST IN U.S. DOLLARS	SINCE FILE ENTRY	TOTAL SESSION
FULL ESTIMATED COST	0.21	0.21

FILE 'REGISTRY' ENTERED AT 15:59:09 ON 11 JUN 2008
USE IS SUBJECT TO THE TERMS OF YOUR STN CUSTOMER AGREEMENT.
PLEASE SEE "HELP USAGETERMS" FOR DETAILS.

Property values tagged with IC are from the ZIC/VINITI data file provided by InfoChem.

STRUCTURE FILE UPDATES: 10 JUN 2008 HIGHEST RN 1027136-44-2
DICTIONARY FILE UPDATES: 10 JUN 2008 HIGHEST RN 1027136-44-2

New CAS Information Use Policies, enter HELP USAGETERMS for details.

TSCA INFORMATION NOW CURRENT THROUGH January 9, 2008.

Please note that search-term pricing does apply when conducting SmartSELECT searches.

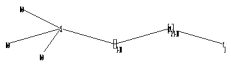
REGISTRY includes numerically searchable data for experimental and predicted properties as well as tags indicating availability of experimental property data in the original document. For information on property searching in REGISTRY, refer to:

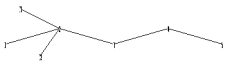
http://www.cas.org/support/stngen/stndoc/properties.html

=> ....Testing the current file.... screen

ENTER SCREEN EXPRESSION OR (END):end

=>
Uploading C:\Program Files\Stnexp\Queries\10765366\str2d.str





chain nodes :
1 5
ring/chain nodes :
2 3 4 11 12
chain bonds :
1-2 4-5
ring/chain bonds :
2-3 2-11 2-12 3-4
exact/norm bonds :
2-3 2-11 2-12 3-4 4-5
exact bonds :
1-2

G1:CH3,CF3

Match level :
1:CLASS 2:CLASS 3:CLASS 4:CLASS 5:CLASS 11:CLASS 12:CLASS

L1 STRUCTURE UPLOADED

=> que L1

L2   QUE L1

=> s l1
SAMPLE SEARCH INITIATED 15:59:32 FILE 'REGISTRY'
SAMPLE SCREEN SEARCH COMPLETED -   562 TO ITERATE

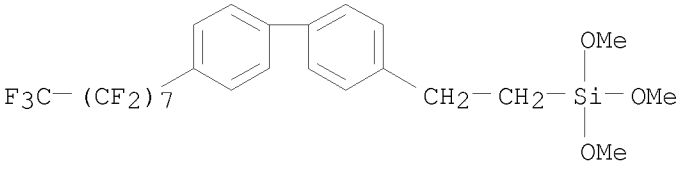
100.0% PROCESSED   562 ITERATIONS   19 ANSWERS
SEARCH TIME: 00.00.01

FULL FILE PROJECTIONS: ONLINE **COMPLETE**
                        BATCH   **COMPLETE**
PROJECTED ITERATIONS: 9818 TO   12662
PROJECTED ANSWERS: 119 TO   641

L3   19 SEA SSS SAM L1

=> d scan 1
'1' IS NOT A VALID FORMAT FOR FILE 'REGISTRY'

L3   19 ANSWERS   REGISTRY COPYRIGHT 2008 ACS on STN
IN   1,1'-Biphenyl, 4-(1,1,2,2,3,3,4,4,5,5,6,6,7,7,8,8,8-heptadecafluorooctyl)-
     4'-[2-(trimethoxysilyl)ethyl]-
MF   C25 H21 F17 O3 Si



PROPERTY DATA AVAILABLE IN THE 'PROP' FORMAT

The following are valid formats:

Substance information can be displayed by requesting individual
fields or predefined formats. The predefined substance formats
are: (RN = CAS Registry Number)

REG   - RN
SAM   - Index Name, MF, and structure - no RN
FIDE   - All substance data, except sequence data
IDE   - FIDE, but only 50 names
SQIDE - IDE, plus sequence data
SQIDE3 - Same as SQIDE, but 3-letter amino acid codes are used
SQD   - Protein sequence data, includes RN
SQD3   - Same as SQD, but 3-letter amino acid codes are used
SQN   - Protein sequence name information, includes RN

CALC   - Table of calculated properties
EPROP - Table of experimental properties
PROP   - EPROP and CALC

Any CA File format may be combined with any substance format to
obtain CA references citing the substance. The substance formats
must be cited first. The CA File predefined formats are:

ABS -- Abstract
APPS -- Application and Priority Information
BIB -- CA Accession Number, plus Bibliographic Data
CAN -- CA Accession Number
CBIB -- CA Accession Number, plus Bibliographic Data (compressed)
IND -- Index Data
IPC -- International Patent Classification
PATS -- PI, SO
STD -- BIB, IPC, and NCL

IABS -- ABS, indented, with text labels
IBIB -- BIB, indented, with text labels
ISTD -- STD format, indented

OBIB -------- AN, plus Bibliographic Data (original)
OIBIB ------- OBIB, indented with text labels

SBIB -------- BIB, no citations
SIBIB ------- IBIB, no citations

The ALL format gives FIDE BIB ABS IND RE, plus sequence data when
it is available.
The MAX format is the same as ALL.
The IALL format is the same as ALL with BIB ABS and IND indented,
with text labels.

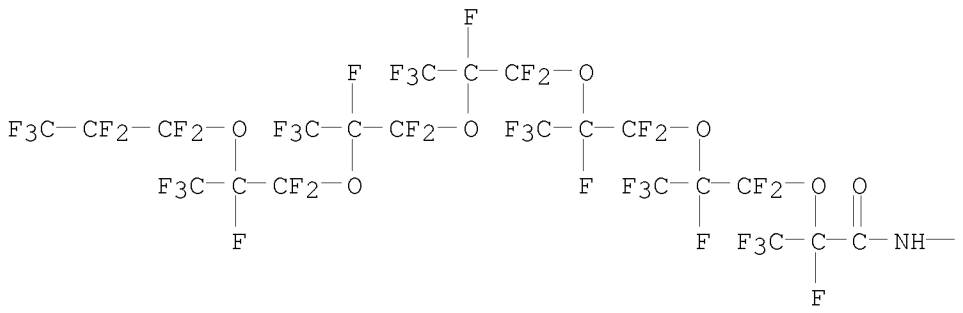
For additional information, please consult the following help
messages:

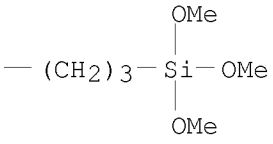
HELP DFIELDS -- To see a complete list of individual display fields.
HELP FORMATS -- To see detailed descriptions of the predefined formats.
HOW MANY MORE ANSWERS DO YOU WISH TO SCAN? (1):1

L3   19 ANSWERS   REGISTRY COPYRIGHT 2008 ACS on STN
IN   2-Propenoic acid, 3-(trimethoxysilyl)propyl ester, polymer with
     α-[dimethyl[2-(trimethoxysilyl)ethyl]silyl]-ω-[[dimethyl[2-
     (trimethoxysilyl)ethyl]silyl]oxy]poly[oxy(dimethylsilylene)],
     (3,3,4,4,5,5,6,6,7,7,8,8,9,9,10,10,10-heptadecafluorodecyl)trimethoxysilan
     e and 2,4,4,5,7,7,8,10,10,11,13,13,14,16,16,17,19,19,20,20,21,21,21-
     tricosafluoro-2,5,8,11,14,17-hexakis(trifluoromethyl)-N-[3-
     (trimethoxysilyl)propyl]-3,6,9,12,15,18-hexaoxaheneicosanamide
MF   (C27 H16 F41 N O10 Si . C13 H13 F17 O3 Si . C9 H18 O5 Si . (C2 H6 O Si)n
     C14 H38 O7 Si4)x
CI   PMS

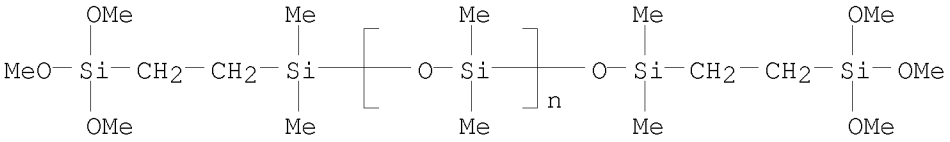
     CM   1

PAGE 1-A

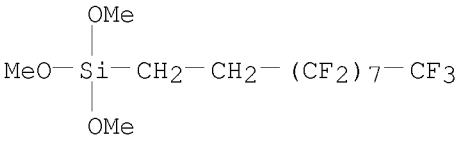




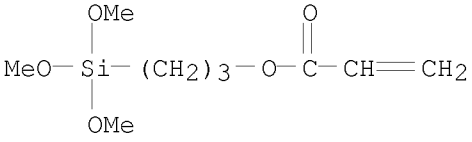
CM 2



CM 3



CM 4



HOW MANY MORE ANSWERS DO YOU WISH TO SCAN? (1):

HOW MANY MORE ANSWERS DO YOU WISH TO SCAN? (1):0

=> s l1 ful
FULL SEARCH INITIATED 16:00:06 FILE 'REGISTRY'
FULL SCREEN SEARCH COMPLETED - 10724 TO ITERATE

100.0% PROCESSED 10724 ITERATIONS 329 ANSWERS
SEARCH TIME: 00.00.01

L4 329 SEA SSS FUL L1

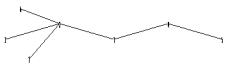
```
=> ....Testing the current file.... screen

ENTER SCREEN EXPRESSION OR (END):end


=> screen 965

L5    SCREEN CREATED

=>
Uploading C:\Program Files\Stnexp\Queries\10765366\str2c.str
```



```
chain nodes :
1  2  3  4  5  6  7
chain bonds :
1-2  2-3  2-6  2-7  3-4  4-5
exact/norm bonds :
4-5
exact bonds :
1-2  2-3  2-6  2-7  3-4


G1:CH3,CF3

Match level :
1:CLASS  2:CLASS  3:CLASS  4:CLASS  5:CLASS  6:CLASS  7:CLASS
```

L6   STRUCTURE UPLOADED

=> que L6 AND L5

L7   QUE L6 AND L5

=> s l7 ful
FULL SEARCH INITIATED 16:00:38 FILE 'REGISTRY'
FULL SCREEN SEARCH COMPLETED -   3302 TO ITERATE

100.0% PROCESSED   3302 ITERATIONS   196 ANSWERS
SEARCH TIME: 00.00.01

L8   196 SEA SSS FUL L6 AND L5

=> s l4 or l8
L9   525 L4 OR L8

=> ....Testing the current file.... screen

ENTER SCREEN EXPRESSION OR (END):end

=> screen 965

L10   SCREEN CREATED

=>
Uploading C:\Program Files\Stnexp\Queries\10765366\str1d.str

chain nodes :
1
ring/chain nodes :
2 3 4 7 8
chain bonds :
1-2
ring/chain bonds :
2-3 2-7 2-8 3-4
exact/norm bonds :
2-3 2-7 2-8 3-4
exact bonds :
1-2

Match level :
1:CLASS 2:CLASS 3:CLASS 4:CLASS 7:CLASS 8:CLASS

L11   STRUCTURE UPLOADED

=> que L11 AND L10

L12 QUE L11 AND L10

=> s l12 ful
FULL SEARCH INITIATED 16:01:08 FILE 'REGISTRY'
FULL SCREEN SEARCH COMPLETED -   89633 TO ITERATE

100.0% PROCESSED   89633 ITERATIONS   12873 ANSWERS
SEARCH TIME: 00.00.01

L13   12873 SEA SSS FUL L11 AND L10

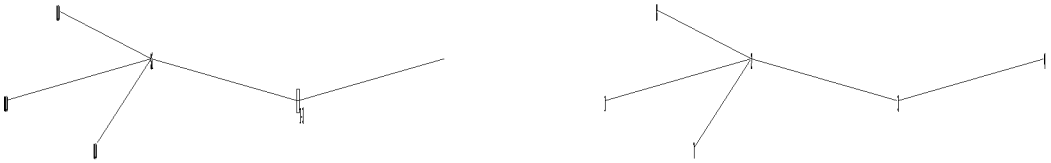
=> ....Testing the current file.... screen

ENTER SCREEN EXPRESSION OR (END):end

=> screen 965

L14   SCREEN CREATED

=>
Uploading C:\Program Files\Stnexp\Queries\10765366\str1d.str



chain nodes :
1
ring/chain nodes :
2 3 4 7 8
chain bonds :
1-2
ring/chain bonds :
2-3 2-7 2-8 3-4
exact/norm bonds :
2-3 2-7 2-8 3-4
exact bonds :
1-2

Match level :
1:CLASS 2:CLASS 3:CLASS 4:CLASS 7:CLASS 8:CLASS

L15   STRUCTURE UPLOADED

=> que L15 AND L14

L16 QUE L15 AND L14

=> s l16 ful
FULL SEARCH INITIATED 16:01:30 FILE 'REGISTRY'
FULL SCREEN SEARCH COMPLETED -   89633 TO ITERATE

100.0% PROCESSED   89633 ITERATIONS   12873 ANSWERS
SEARCH TIME: 00.00.01

```
L17       12873 SEA SSS FUL L15 AND L14

=> s l13 or l17
L18       12873 L13 OR L17

=> s l18 and l9
L19         229 L18 AND L9

=> file caplus
COST IN U.S. DOLLARS                                SINCE FILE      TOTAL
                                                         ENTRY    SESSION
FULL ESTIMATED COST                                     713.90     714.11

FILE 'CAPLUS' ENTERED AT 16:02:05 ON 11 JUN 2008
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FILE COVERS 1907 - 11 Jun 2008  VOL 148 ISS 24
FILE LAST UPDATED: 10 Jun 2008  (20080610/ED)

Effective October 17, 2005, revised CAS Information Use Policies apply.
They are available for your review at:

http://www.cas.org/legal/infopolicy.html

=> s l19
L20         795 L19

=> dup remove l20
PROCESSING COMPLETED FOR L20
L21          794 DUP REMOVE L20 (1 DUPLICATE REMOVED)

=> s l21 and silicon
L22         794 S L21
         883161 SILICON
            421 SILICONS
         883305 SILICON
                   (SILICON OR SILICONS)
L23         140 L22 AND SILICON

=> dup remove l23
PROCESSING COMPLETED FOR L23
L24          140 DUP REMOVE L23 (0 DUPLICATES REMOVED)

=> s l24 and (vapor or cvd or pecvd)
L25         140 S L24
         564157 VAPOR
          74017 VAPORS
         607606 VAPOR
                   (VAPOR OR VAPORS)
```

```
         76827 CVD
            83 CVDS
         76848 CVD
                 (CVD OR CVDS)
          8624 PECVD
L26         25 L25 AND (VAPOR OR CVD OR PECVD)

=> dup remove l26
PROCESSING COMPLETED FOR L26
L27          25 DUP REMOVE L26 (0 DUPLICATES REMOVED)

=> d ti 1-25

L27  ANSWER 1 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Layer-by-layer fabrication of broad-band super-hydrophobic antireflection
     coatings in near-infrared region

L27  ANSWER 2 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Digital magnetofluidic devices and methods

L27  ANSWER 3 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Method of processing a biological and/or chemical sample

L27  ANSWER 4 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Thin organic alignment layers with a batch process for liquid crystal
     displays

L27  ANSWER 5 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Atmospheric plasma deposition of hydrophobic/oil-repellent coatings with
     improved durability on glass/ceramic windows

L27  ANSWER 6 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Method for constructing surface enhanced substrate with metal ordered
     structure

L27  ANSWER 7 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Method for identical dye molecule emitting different color fluorescent
     light by substrate induction

L27  ANSWER 8 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Surface engineering of poly(dimethylsiloxane) micro fluidic devices using
     transition metal sol-gel chemistry

L27  ANSWER 9 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Thermal stability of vapor phase deposited self-assembled
     monolayers for MEMS anti-stiction

L27  ANSWER 10 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Surface modification of silicon and polydimethylsiloxane
     surfaces with vapor-phase-deposited ultrathin fluorosilane films
     for biomedical nanodevices

L27  ANSWER 11 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Rain-proof glass windows with a silicon-containing hydrophobic
     surface of improved durability

L27  ANSWER 12 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
TI   Micropatterning of SrBi2Ta2O9 ferroelectric thin films using a selective
     deposition technique combined with patterned self-assembled monolayers and
     liquid-source misted chemical deposition

L27  ANSWER 13 OF 25  CAPLUS  COPYRIGHT 2008 ACS on STN
```

TI Nanoscale patterning of protein using electron beam lithography of organosilane self-assembled monolayers

L27 ANSWER 14 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Liquid and vapor phase silanes coating for the release of thin film MEMS

L27 ANSWER 15 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Thin film forming method and thin film forming substance

L27 ANSWER 16 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Method of coating microelectromechanical devices

L27 ANSWER 17 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Method and apparatus for manufacturing anti-reflective films

L27 ANSWER 18 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Vapor pressures of precursors for the CVD of silicon-based films

L27 ANSWER 19 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Self-assembled monolayer coatings on nanostencils for the reduction of materials adhesion

L27 ANSWER 20 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Method for making thin film and electronic apparatus

L27 ANSWER 21 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Formation method of silicon thin film

L27 ANSWER 22 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Method for providing water-repellent coatings on optical substrates

L27 ANSWER 23 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Vapor Phase Self-Assembly of Fluorinated Monolayers on Silicon and Germanium Oxide

L27 ANSWER 24 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Water-repellent fluorine-containing silicon oxide coatings

L27 ANSWER 25 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
TI Heat- and chemical-resistant organic thin films and their manufacture

=> d bib 1-25

L27 ANSWER 1 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2008:78111 CAPLUS
DN 148:333398
TI Layer-by-layer fabrication of broad-band super-hydrophobic antireflection coatings in near-infrared region
AU Zhang, Lianbin; Li, Yang; Sun, Junqi; Shen, Jiacong
CS State Key Lab of Supramolecular Structure and Materials, College of Chemistry, Jilin University, Changchun, 130012, Peop. Rep. China
SO Journal of Colloid and Interface Science (2008), 319(1), 302-308
CODEN: JCISA5; ISSN: 0021-9797
PB Elsevier
DT Journal
LA English
RE.CNT 49 THERE ARE 49 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 2 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2007:1000213 CAPLUS
DN 147:355832
TI Digital magnetofluidic devices and methods
IN Hernandez, Sonia Melle; Gomez, Ana N.; Picraux, S. Thomas; Gust, John Devens; Hayes, Mark; Lindsay, Solitaire; Garcia, Antonio A.; Wang, Joseph; Vazquez-Alvarez, Terannie
PA Arizona Board of Regents for and on Behalf of Arizona State University, USA
SO PCT Int. Appl., 118pp.
CODEN: PIXXD2
DT Patent
LA English
FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI WO 2007101174	A2	20070907	WO 2007-US62842	20070227
WO 2007101174	A3	20071221		

W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LA, LC, LK, LR, LS, LT, LU, LV, LY, MA, MD, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RS, RU, SC, SD, SE, SG, SK, SL, SM, SV, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW
RW: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM, AP, EA, EP, OA

PRAI US 2006-777679P P 20060227

L27 ANSWER 3 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2007:933138 CAPLUS
DN 147:290978
TI Method of processing a biological and/or chemical sample
IN Pipper, Juergen; Hsieh, Tseng-Ming; Neuzil, Pavel
PA Agency for Science, Technology and Research, Singapore
SO PCT Int. Appl., 67pp.
CODEN: PIXXD2
DT Patent
LA English
FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI WO 2007094739	A1	20070823	WO 2006-SG29	20060213

W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, LY, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SM, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW
RW: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM

PRAI WO 2006-SG29 20060213
RE.CNT 5 THERE ARE 5 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 4 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2007:970042 CAPLUS
DN 147:288568
TI Thin organic alignment layers with a batch process for liquid crystal displays
IN Ong, Hiap L.
PA Kyoritsu Optronics Co., Ltd., Taiwan
SO U.S. Pat. Appl. Publ., 16pp., Cont.-in-part of U.S. Ser. No. 227,570.
CODEN: USXXCO
DT Patent
LA English
FAN.CNT 2

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	US 20070202253	A1	20070830	US 2006-607246	20061201
	US 20070059438	A1	20070315	US 2005-227570	20050915
	CN 101191198	A	20080604	CN 2007-10165733	20071106
PRAI	US 2005-227570	A2	20050915		
	US 2006-607246	A	20061201		

L27 ANSWER 5 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2007:1449167 CAPLUS
DN 148:83928
TI Atmospheric plasma deposition of hydrophobic/oil-repellent coatings with improved durability on glass/ceramic windows
IN Durandeau, Anne; Montigaud, Herve; Abbott, Fabrice; Huignard, Arnaud
PA Saint-Gobain Glass France, Fr.
SO Fr. Demande, 28pp.
CODEN: FRXXBL
DT Patent
LA French
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	FR 2902422	A1	20071221	FR 2006-52159	20060616
	WO 2007144536	A1	20071221	WO 2007-FR51421	20070612
	W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BH, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DO, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LA, LC, LK, LR, LS, LT, LU, LY, MA, MD, ME, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RS, RU, SC, SD, SE, SG, SK, SL, SM, SV, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW				
	RW: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, LV, MC, MT, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG, BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM				
PRAI	FR 2006-52159	A	20060616		

RE.CNT 3 THERE ARE 3 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 6 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2007:980718 CAPLUS
DN 147:376451
TI Method for constructing surface enhanced substrate with metal ordered structure
IN Lu, Nan; Yang, Bingjie; Huang, Chunyu; Chi, Lifeng
PA Jilin University, Peop. Rep. China
SO Faming Zhuanli Shenqing Gongkai Shuomingshu, 30pp.
CODEN: CNXXEV
DT Patent

LA Chinese
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	CN 101024483	A	20070829	CN 2007-10055453	20070327
PRAI	CN 2007-10055453		20070327		

L27 ANSWER 7 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2006:1085199 CAPLUS
DN 146:35674
TI Method for identical dye molecule emitting different color fluorescent light by substrate induction
IN Lu, Nan; Hu, Wei; Hao, Juanyuan; Chi, Lifeng
PA Jilin University, Peop. Rep. China
SO Faming Zhuanli Shenqing Gongkai Shuomingshu, 24pp.
CODEN: CNXXEV
DT Patent
LA Chinese
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	CN 1844300	A	20061011	CN 2006-10016744	20060404
PRAI	CN 2006-10016744		20060404		

L27 ANSWER 8 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2006:277375 CAPLUS
DN 144:489687
TI Surface engineering of poly(dimethylsiloxane) micro fluidic devices using transition metal sol-gel chemistry
AU Roman, Gregory T.; Culbertson, Christopher T.
CS Department of Chemistry, Kansas State University, Manhattan, KS, 66506, USA
SO Langmuir (2006), 22(9), 4445-4451
CODEN: LANGD5; ISSN: 0743-7463
PB American Chemical Society
DT Journal
LA English
RE.CNT 86 THERE ARE 86 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 9 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2006:1341743 CAPLUS
DN 147:475337
TI Thermal stability of vapor phase deposited self-assembled monolayers for MEMS anti-stiction
AU Zhuang, Yan Xin; Hansen, Ole; Knieling, Thomas; Wang, Christian; Rombach, Pirmin; Lang, Walter; Benecke, Wolfgang; Kehlenbeck, Markus; Koblitz, Joern
CS CINF, MIC-Department of Micro and Nanotechnology, Technical University of Denmark, Lyngby, DK-2800, Den.
SO Journal of Micromechanics and Microengineering (2006), 16(11), 2259-2264
CODEN: JMMIEZ; ISSN: 0960-1317
PB Institute of Physics Publishing
DT Journal
LA English
RE.CNT 22 THERE ARE 22 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 10 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2006:641508 CAPLUS
DN 145:183229
TI Surface modification of silicon and polydimethylsiloxane

surfaces with vapor-phase-deposited ultrathin fluorosilane films for biomedical nanodevices
AU Bhushan, Bharat; Hansford, Derek; Lee, Kang Kug
CS Nanotribology Laboratory for Information Storage and MEMS/NEMS, The Ohio State University, Columbus, OH, 43202, USA
SO Journal of Vacuum Science & Technology, A: Vacuum, Surfaces, and Films (2006), 24(4), 1197-1202
CODEN: JVTAD6; ISSN: 0734-2101
PB American Institute of Physics
DT Journal
LA English
RE.CNT 10 THERE ARE 10 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 11 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2005:902015 CAPLUS
DN 143:233933
TI Rain-proof glass windows with a silicon-containing hydrophobic surface of improved durability
IN Duran, Maxime; Huignard, Arnaud
PA Saint-Gobain Glass France, Fr.
SO Fr. Demande, 32 pp.
CODEN: FRXXBL
DT Patent
LA French
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	FR 2866643	A1	20050826	FR 2004-50343	20040224
	FR 2866643	B1	20060526		
	WO 2005084943	A2	20050915	WO 2005-FR50119	20050223
	WO 2005084943	A3	20051103		
	W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SM, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW				
	RW: BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM, AZ, BY, KG, KZ, MD, RU, TJ, TM, AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG				
	EP 1720808	A2	20061115	EP 2005-728106	20050223
	R: AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HU, IE, IS, IT, LI, LT, LU, MC, NL, PL, PT, RO, SE, SI, SK, TR				
	CN 1946646	A	20070411	CN 2005-80012900	20050223
	BR 2005007935	A	20070717	BR 2005-7935	20050223
	JP 2007523776	T	20070823	JP 2007-500274	20050223
	IN 2006KN02325	A	20070525	IN 2006-KN2325	20060817
	MX 2006PA09574	A	20061107	MX 2006-PA9574	20060823
PRAI	FR 2004-50343	A	20040224		
	WO 2005-FR50119	W	20050223		

RE.CNT 2 THERE ARE 2 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 12 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2005:410625 CAPLUS
DN 143:88377
TI Micropatterning of SrBi2Ta2O9 ferroelectric thin films using a selective deposition technique combined with patterned self-assembled monolayers and liquid-source misted chemical deposition

AU Takakuwa, Atsushi; Ishida, Masaya; Shimoda, Tatsuya
CS Technology Platform Research Center, SEIKO EPSON Corporation, Nagano, 399-0293, Japan
SO Japanese Journal of Applied Physics, Part 1: Regular Papers, Short Notes & Review Papers (2005), 44(4A), 1897-1900
CODEN: JAPNDE
PB Japan Society of Applied Physics
DT Journal
LA English
RE.CNT 8 THERE ARE 8 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 13 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2005:702603 CAPLUS
DN 144:208350
TI Nanoscale patterning of protein using electron beam lithography of organosilane self-assembled monolayers
AU Zhang, Guo-Jun; Tanii, Takashi; Zako, Tamotsu; Hosaka, Takumi; Miyake, Takeo; Kanari, Yuzo; Funatsu, Takashi; Ohdomari, Iwao
CS Nanotechnology Research Center and Institute of Biomedical Engineering, Waseda University, Tokyo, 162-0041, Japan
SO Small (2005), 1(8-9), 833-837
CODEN: SMALBC; ISSN: 1613-6810
PB Wiley-VCH Verlag GmbH & Co. KGaA
DT Journal
LA English
RE.CNT 22 THERE ARE 22 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 14 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2006:143210 CAPLUS
DN 144:499593
TI Liquid and vapor phase silanes coating for the release of thin film MEMS
AU Parvais, B.; Pallandre, A.; Jonas, A. M.; Raskin, J.-P.
CS Research Center in Micro and Nanoscopic Materials and Electronic Devices (CERMIN), Universite catholique de Louvain, Louvain-la-Neuve, B-1348, Belg.
SO IEEE Trans. Device Mater. Reliab. (2005), 5(2), 250-254
CODEN: ITDMA2; ISSN: 1530-4388
URL: http://ieeexplore.ieee.org/iel5/7298/31396/01458741.pdf?isnumber=31396&prod=JNL&arnumber=1458741&arSt=+250&ared=+254&arAuthor=Parvais%2C+B.%3B+Pallandre%2C+A.%3B+Jonas%2C+A.M.%3B+Raskin%2C+J.-P.
PB Institute of Electrical and Electronics Engineers
DT Journal; (online computer file)
LA English
RE.CNT 18 THERE ARE 18 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 15 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2004:1060574 CAPLUS
DN 142:40141
TI Thin film forming method and thin film forming substance
IN Kudo, Ichiro; Saito, Atsushi; Arita, Hiroaki
PA Konica Minolta Holdings, Inc., Japan
SO U.S. Pat. Appl. Publ., 32 pp.
CODEN: USXXCO
DT Patent
LA English
FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
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PI US 20040247886 A1 20041209 US 2004-858704 20040601
    JP 2004360039 A 20041224 JP 2003-162032 20030606
    JP 2005023381 A 20050127 JP 2003-191025 20030703
    WO 2004108984 A1 20041216 WO 2004-JP7860 20040531
        W: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH,
            CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD,
            GE, GH, GM, HR, HU, ID, IL, IN, IS, KE, KG, KP, KR, KZ, LC, LK,
            LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NA, NI, NO,
            NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SY, TJ,
            TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW
        RW: BW, GH, GM, KE, LS, MW, MZ, NA, SD, SL, SZ, TZ, UG, ZM, ZW, AM,
            AZ, BY, KG, KZ, MD, RU, TJ, TM, AT, BE, BG, CH, CY, CZ, DE, DK,
            EE, ES, FI, FR, GB, GR, HU, IE, IT, LU, MC, NL, PL, PT, RO, SE,
            SI, SK, TR, BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE,
            SN, TD, TG
    EP 1643002 A1 20060405 EP 2004-735520 20040531
        R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT,
            IE, SI, LT, LV, FI, RO, MK, CY, AL, TR, BG, CZ, EE, HU, PL, SK, HR
    CN 1798865 A 20060705 CN 2004-80015446 20040531
PRAI JP 2003-162032 A 20030606
    JP 2003-191025 A 20030703
    WO 2004-JP7860 W 20040531

L27 ANSWER 16 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2004:162231 CAPLUS
DN 140:227524
TI Method of coating microelectromechanical devices
IN Yang, Zhihao
PA Eastman Kodak Company, USA
SO U.S. Pat. Appl. Publ., 7 pp.
    CODEN: USXXCO
DT Patent
LA English
FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
US 20040037956	A1	20040226	US 2002-225846	20020822
US 6808745	B2	20041026		
EP 1416064	A2	20040506	EP 2003-77499	20030811
EP 1416064	A3	20050615		
EP 1416064	B1	20080507		
R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO, MK, CY, AL, TR, BG, CZ, EE, HU, SK				
JP 2004084073	A	20040318	JP 2003-298568	20030822

PRAI US 2002-225846 A 20020822
RE.CNT 7 THERE ARE 7 CITED REFERENCES AVAILABLE FOR THIS RECORD
          ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 17 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2004:198553 CAPLUS
DN 140:236678
TI Method and apparatus for manufacturing anti-reflective films
IN Tanaka, Takeshi
PA Konica Minolta Holdings Inc., Japan
SO Jpn. Kokai Tokkyo Koho, 40 pp.
    CODEN: JKXXAF
DT Patent
LA Japanese
FAN.CNT 1

PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
JP 2004075738	A	20040311	JP 2002-234607	20020812

PRAI JP 2002-234607 20020812

L27 ANSWER 18 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2004:157226 CAPLUS
DN 140:383314
TI Vapor pressures of precursors for the CVD of silicon-based films
AU Alcott, Gregory R.; van de Sanden, Richard M. C. M.; Kondic, Sascha; Linden, Joannes L.
CS Department of Applied Physics, Eindhoven University of Technology, Eindhoven, 5600 MB, Neth.
SO Chemical Vapor Deposition (2004), 10(1), 20-22
CODEN: CVDEFX; ISSN: 0948-1907
PB Wiley-VCH Verlag GmbH & Co. KGaA
DT Journal
LA English
RE.CNT 6 THERE ARE 6 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 19 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2003:256239 CAPLUS
DN 139:37976
TI Self-assembled monolayer coatings on nanostencils for the reduction of materials adhesion
AU Kolbel, Marius; Tjerkstra, R. Willem; Kim, Gyuman; Brugger, Jurgen; van Rijn, Cees J. M.; Nijdam, Wietze; Huskens, Jurriaan; Reinhoudt, David N.
CS Laboratory of Supramolecular Chemistry and Technology MESA+ Research Institute, University of Twente, Enschede, NL-7500 AE, Neth.
SO Advanced Functional Materials (2003), 13(3), 219-224
CODEN: AFMDC6; ISSN: 1616-301X
PB Wiley-VCH Verlag GmbH & Co. KGaA
DT Journal
LA English
RE.CNT 17 THERE ARE 17 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 20 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2002:638152 CAPLUS
DN 137:177507
TI Method for making thin film and electronic apparatus
IN Furusawa, Masahiro; Shimoda, Tatsuya
PA Seiko Epson Corporation, Japan
SO U.S. Pat. Appl. Publ., 13 pp.
CODEN: USXXCO
DT Patent
LA English
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	US 20020114887	A1	20020822	US 2001-26635	20011227
	US 6780465	B2	20040824		
	JP 2002275629	A	20020925	JP 2001-398535	20011227
PRAI	JP 2000-403229	A	20001228		

RE.CNT 5 THERE ARE 5 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 21 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 2002:539411 CAPLUS
DN 137:101690
TI Formation method of silicon thin film
IN Furusawa, Masahiro; Miyashita, Satoru; Yudasaka, Kazuo; Shimoda, Tatsuya; Yokoyama, Yasuaki; Matsuki, Yasuo; Takeuchi, Yasumasa

PA Seiko Epson Corp., Japan; JSR Ltd.
SO Jpn. Kokai Tokkyo Koho, 7 pp.
CODEN: JKXXAF
DT Patent
LA Japanese
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	JP 2002203794	A	20020719	JP 2000-402809	20001228
	JP 3745959	B2	20060215		
	US 20030087110	A1	20030508	US 2001-28712	20011228
	US 6846513	B2	20050125		
PRAI	JP 2000-402809	A	20001228		

OS MARPAT 137:101690

L27 ANSWER 22 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 1999:783781 CAPLUS
DN 132:37023
TI Method for providing water-repellent coatings on optical substrates
IN Anthes, Uwe; Dombrowski, Reiner
PA Merck Patent G.m.b.H., Germany
SO Eur. Pat. Appl., 8 pp.
CODEN: EPXXDW
DT Patent
LA German
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	EP 962511	A1	19991208	EP 1999-110077	19990522
	EP 962511	B1	20051116		
	R: AT, BE, CH, DE, DK, ES, FR, GB, GR, IT, LI, LU, NL, SE, MC, PT, IE, SI, LT, LV, FI, RO				
	DE 19825100	A1	19991216	DE 1998-19825100	19980605
	ES 2252887	T3	20060516	ES 1999-110077	19990522
	JP 2000080331	A	20000321	JP 1999-153778	19990601
	JP 3549440	B2	20040804		
	KR 2000005904	A	20000125	KR 1999-20580	19990604
	US 6296793	B1	20011002	US 1999-325796	19990604
	US 20010033893	A1	20011025	US 2001-892712	20010628
PRAI	DE 1998-19825100	A	19980605		
	US 1999-325796	A3	19990604		

OS MARPAT 132:37023
RE.CNT 6 THERE ARE 6 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 23 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN 1997:178996 CAPLUS
DN 126:298032
OREF 126:57613a,57616a
TI Vapor Phase Self-Assembly of Fluorinated Monolayers on Silicon and Germanium Oxide
AU Hoffmann, Patrick W.; Stelzle, Martin; Rabolt, John F.
CS IBM Almaden Research Center, San Jose, CA, 95120, USA
SO Langmuir (1997), 13(7), 1877-1880
CODEN: LANGD5; ISSN: 0743-7463
PB American Chemical Society
DT Journal
LA English
RE.CNT 21 THERE ARE 21 CITED REFERENCES AVAILABLE FOR THIS RECORD
ALL CITATIONS AVAILABLE IN THE RE FORMAT

L27 ANSWER 24 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN

AN   1995:330786 CAPLUS
DN   122:108850
OREF 122:20441a,20444a
TI   Water-repellent fluorine-containing silicon oxide coatings
IN   Sumi, Toshio; Matsuda, Atsunori; Ogino, Etsuo; Soejima, Ayako
PA   Nippon Sheet Glass Co Ltd, Japan
SO   Jpn. Kokai Tokkyo Koho, 7 pp.
     CODEN: JKXXAF
DT   Patent
LA   Japanese
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	JP 06228755	A	19940816	JP 1993-16332	19930203
PRAI	JP 1993-16332		19930203		

L27 ANSWER 25 OF 25 CAPLUS COPYRIGHT 2008 ACS on STN
AN   1994:109608 CAPLUS
DN   120:109608
OREF 120:19339a,19342a
TI   Heat- and chemical-resistant organic thin films and their manufacture
IN   Morikawa, Juko; Kasanuki, Juji; Yanagisawa, Yoshihiro; Matsuda, Hiroshi
PA   Canon Kk, Japan
SO   Jpn. Kokai Tokkyo Koho, 8 pp.
     CODEN: JKXXAF
DT   Patent
LA   Japanese
FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PI	JP 05220887	A	19930831	JP 1992-28417	19920214
	JP 3025091	B2	20000327		
PRAI	JP 1992-28417		19920214		

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ALL L# QUERIES AND ANSWER SETS ARE DELETED AT LOGOFF
LOGOFF? (Y)/N/HOLD:y

COST IN U.S. DOLLARS	SINCE FILE ENTRY	TOTAL SESSION
FULL ESTIMATED COST	48.69	762.80

STN INTERNATIONAL LOGOFF AT 16:03:30 ON 11 JUN 2008